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I hereby certify that this correspondence is being deposited with the United States Postal Service JC17 Rec'd PCT/PTO 2 1 SEP 2005 as Express mail in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on September 21, 2005.

PATENT

H. Boswels Stacis Stacie H. Boswell Date of Signature

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Johnson et al.

Group Art Unit: N/A

Serial No.: N/A

Examiner: N/A

Filed: Herewith

Docket No.: 297/172 PCT/US

Confirmation No.: N/A

METHODS FOR NANOSCALE STRUCTURES FROM OPTICAL LITHOGRAPHY For:

AND SUBSEQUENT LATERAL GROWTH

INFORMATION DISCLOSURE STATEMENT

* * * * * * * * * * *

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In accordance with 37 C.F.R. 1.56, 1.97, and 1.98, applicants' undersigned attorney brings to the attention of the Patent and Trademark Office the documents listed on the attached Form PTO-1449. Copies of the references as well as Form PTO-1449 are attached hereto. This is not to be construed as a representation that a search has been made or that a reference is relevant merely because cited.

Early passage of the subject application to issue is earnestly solicited.

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Although it is believed that no fee is due, the Commissioner is hereby authorized to charge any fees associated with the filing of this Information Disclosure Statement to Deposit Account No. <u>50-0426</u>.

Respectfully submitted,

JENKINS, WILSON & TAYLOR, P.A.

Date: 21 Sept. 2005

By:

Jeffrey L. Wilson

Registration No. 36,058

JLW/shb

Enclosures

Customer No: 25297

JC17 Rec'd PCT/PTO 21 SEP 2005 Sheet For 2

FORM PTO-1449 U.S. Department of Commerce Patent and Trademark Office List of Documents Cited by Applicant	Attorney Docket No. 297/172 PCT/US / Serial No 550 1.7		
	Applicant(s): Johnson et al.		
	Filing Date: Herewith	Group	

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing date if Appropriate
	1.	6,709,929	03/23/2004	Zhang et al.			
	2.	6,593,065	07/15/2003	Scherer			
	3.	6,214,246	04/10/2001	Craighead			
	4.	5,151,757	09/29/1992	Enoki et al.			
	5.	5,838,030	11/17/1998	Liu et al.			
	6.	6,242,293	06/05/2001	Danzilio			
	7.	6,008,509	12/28/1999	Inai et al.			
	8.	6,309,580	10/30/2001	Chou			
	9.	6,566,704	05/20/2003	Choi et al.			
	10.	6,593,065	07/15/2003	Scherer			
	11.	6,755,984	06/29/2004	Lee et al.			
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EXAMINER	DATE CONSIDERED
LAAMINLIN	DATE CONCIDENCE

^{*}Examiner Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.